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APPLICANTS										
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Riichiro Takahashi, Kanagawa-ken, JAPAN; Tatsuhiko Ema, Kanagawa-ken, JAPAN;Katsuya Okamura, Kanagawa-ken, JAPAN;										
*** CONTINUING DATA *****  This application is a DIV of 10/396,407 03/26/2003 PAT 6,709,531 which is a DIV of 09/784,200 02/16/2001 PAT 6,579,382  *** FOREIGN APPLICATIONS ****  JAPAN P2000-39683 02/17/2000 JAPAN P2000-297441 09/28/2000  IF REQUIRED, FOREIGN FILING LICENSE GRANTED *** 05/10/2004										
Foreign Priority claimed 35 USC 119 (a-d) condit		⊠ yes □ no □ Met afte	^,	STATE OR	SH	IEETS	тоти	AL	INDEPENDENT	
met Verified and Acknowledged		Allowance	1C tials	COUNTRY JAPAN	DRA	AWING 18	CLAIN 20		CLAIMS 2	
ADDRESS 22852 FINNEGAN, HENDERSON, FARABOW, GARRETT & DUNNER LLP 901 NEW YORK AVENUE, NW WASHINGTON, DC 20001-4413										
Chemical liquid processing apparatus for processing a substrate and the method thereof										
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